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**Bib Data Sheet** FILING DATE **ATTORNEY** CLASS **GROUP ART UNIT SERIAL NUMBER** 08/28/2001 DOCKET NO. 09/940,819 356 2877 **RULE** NL000770 APPLICANTS Rene Monshouwer, Eindhoven, NETHERLANDS; Jacobus Hermanus Maria Neijzen, Eindhoven, NETHERLANDS; Jan Evert Van der werf, Eindhoven, NETHERLANDS; \* CONTINUING DATA \*\*\*\*\*\*\*\*\*\*\*\*\*\*\*\*\*\* \* FOREIGN APPLICATIONS \*\*\*\*\*\*\*\*\*\*\*\*\* EUROPEAN PATENT OFFICE (EPO) 00204825.4 12/27/2000 IF REQUIRED, FOREIGN FILING LICENSE GRANTED \* 10/05/2001 Foreign Priority claimed ves no STATE OR SHEETS TOTAL INDEPENDENT ☐ yes ☐ no ☐ Met after 35 USC 119 (a-d) conditions COUNTRY **DRAWING CLAIMS CLAIMS** NETHERLANDS 9 Verified and Acknowledged Examiner's Signature Initials ADDRESS Corporate Patent Counsel U.S. Philips Corporation 580 White Plains Road Tarrytown ,NY 10591 TITLE Method of measuring alignment of a substrate with respect to a reference alignment mark ☐ All Fees 📕 1.16 Fees ( Filing ) ☐ 1.17 Fees ( Processing Ext. of **FILING FEE** FEES: Authority has been given in Paper No. \_\_\_\_\_\_to charge/credit DEPOSIT ACCOUNT No. \_\_\_\_\_\_for following: time) **RECEIVED** 710 1.18 Fees (Issue) Other ☐ Credit